

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Ken OZAWA

Application No.: 09/711,944

Filed: November 15, 2000

Docket No.: 107878

For: METHOD AND APPARATUS FOR PROJECTION EXPOSURE AND DEVICE
MANUFACTURING METHOD#2
6 Apr 01
R. TalluINFORMATION DISCLOSURE STATEMENTDirector of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of the non-English language reference is discussed in the present specification.
- ☒ 3. U.S. Patent No. 5,627,627 corresponds with Japanese Patent Application, First Publication Hei. 6-25022.

Respectfully submitted,

James A. Oliff
Registration No. 27,975Joel S. Armstrong
Registration No. 36,430JAO:JSA/zmc
Date: February 6, 2001OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400DEPOSIT ACCOUNT USE
AUTHORIZATIONPlease grant any extension
necessary for entry;Charge any fee due to our
Deposit Account No. 15-0461